

Fig. 2

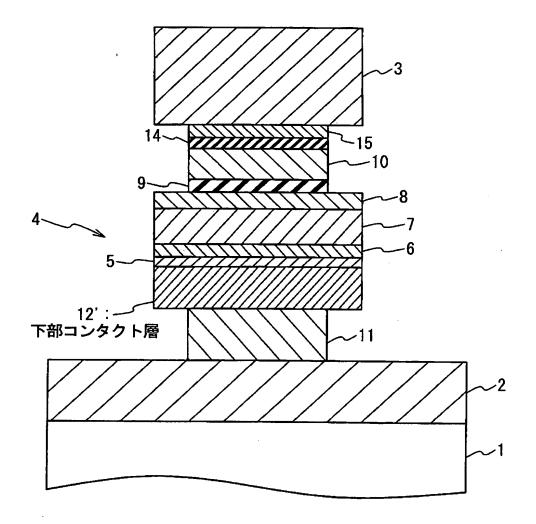
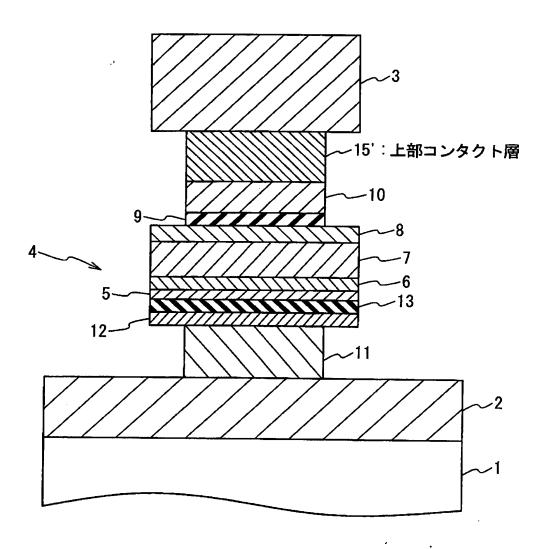


Fig. 3



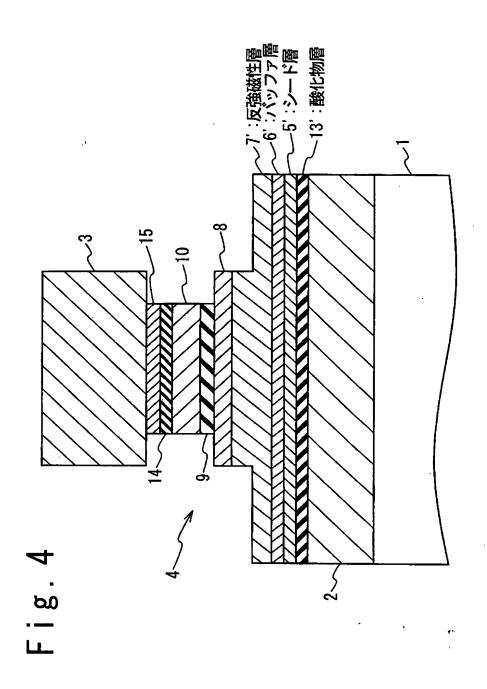


Fig. 5

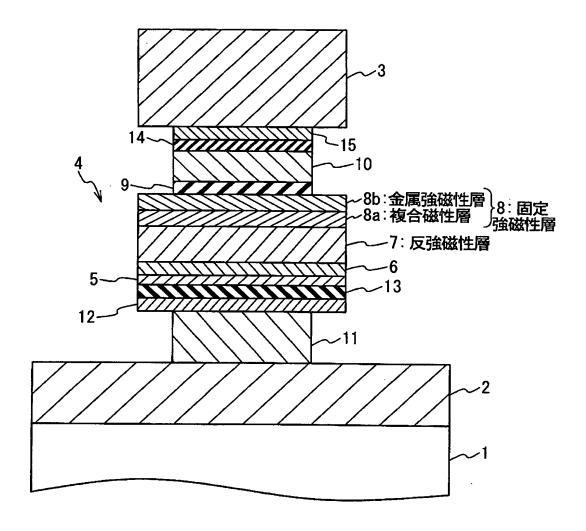


Fig. 6A

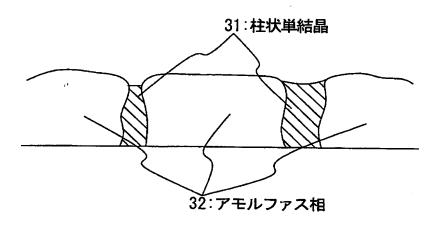


Fig. 6B

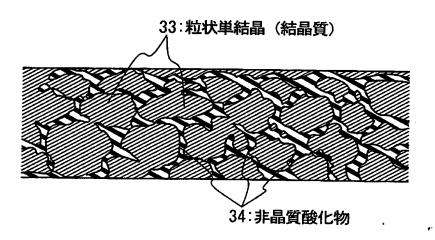


Fig. 7

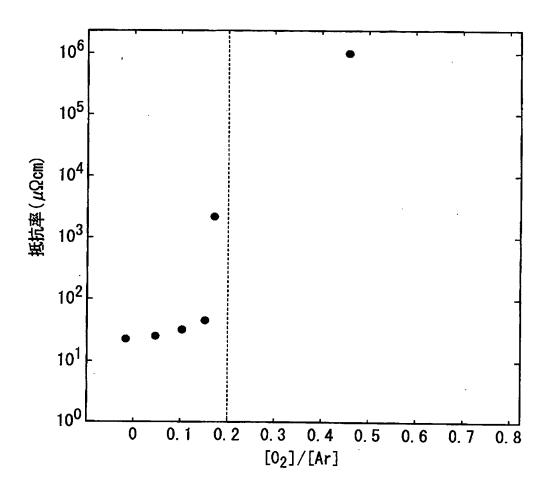


Fig. 8

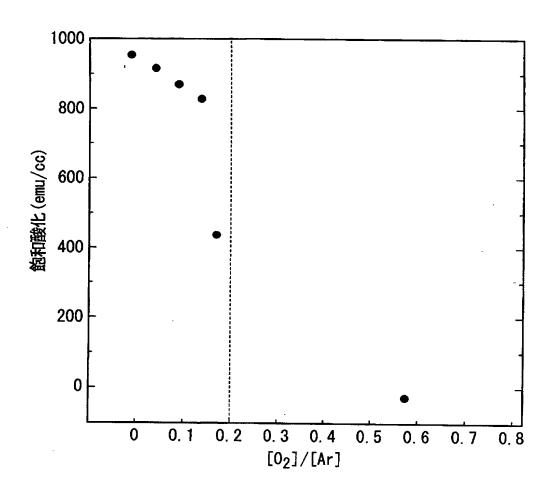


Fig. 9

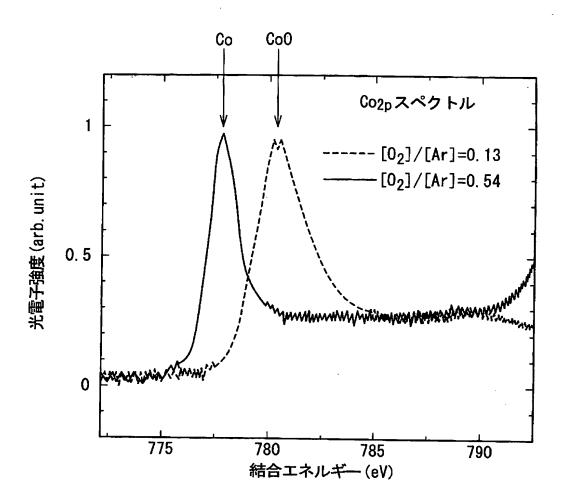


Fig. 10

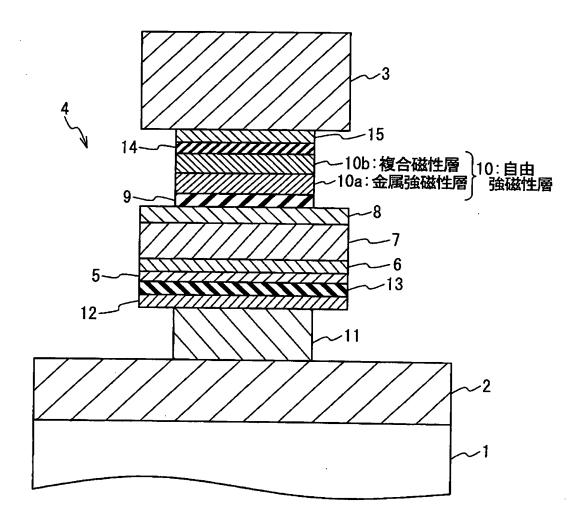


Fig. 11

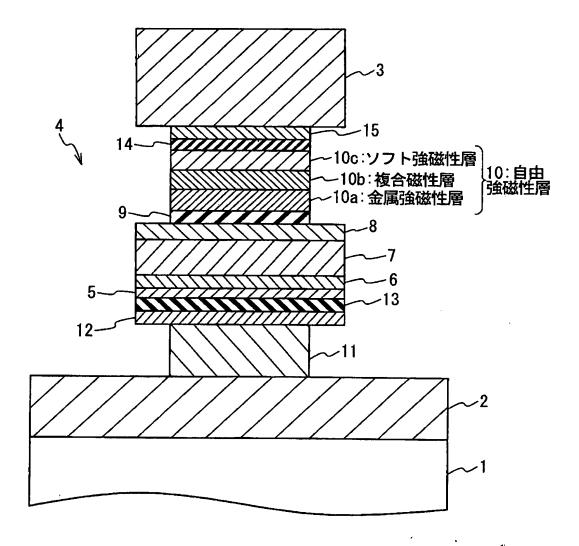


Fig. 12

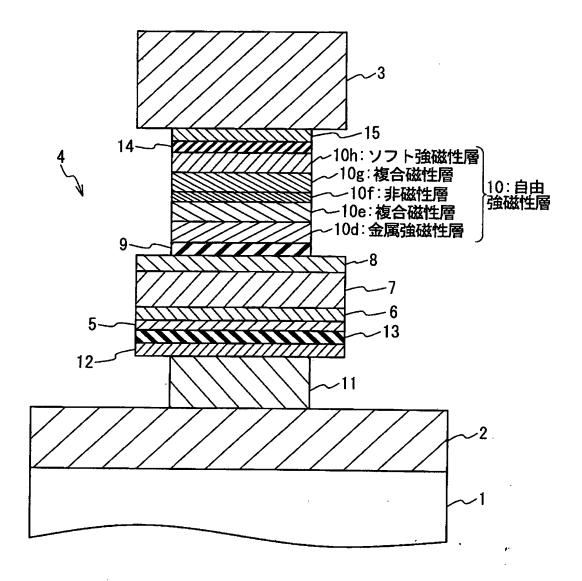


Fig. 13

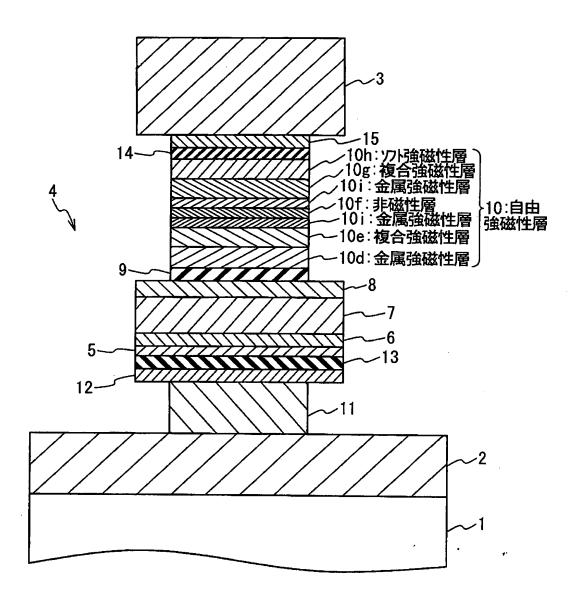


Fig. 14

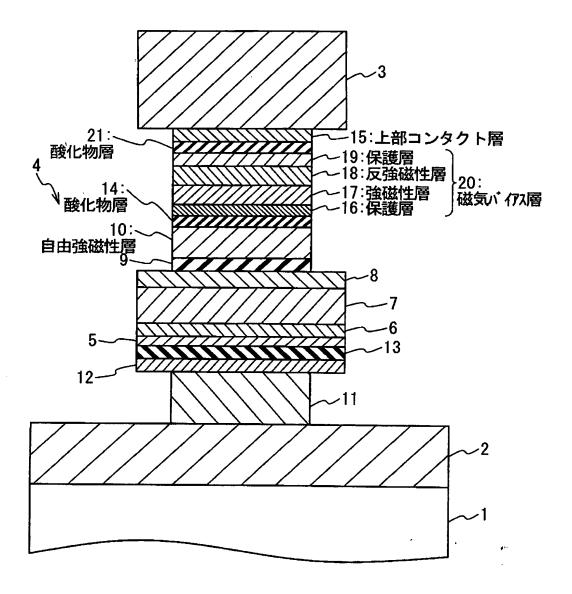
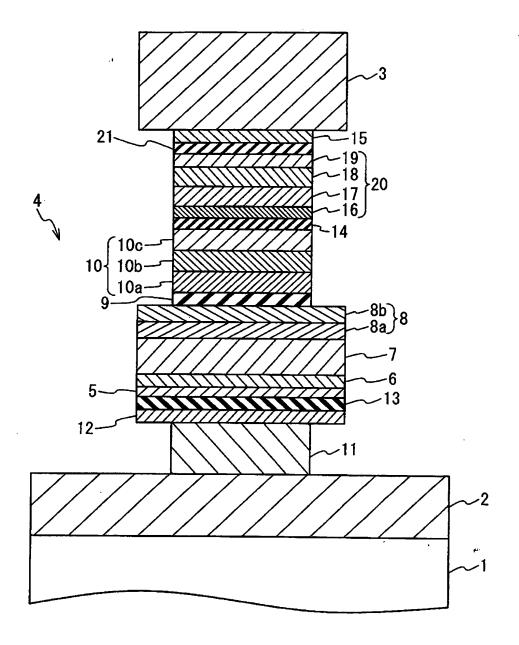
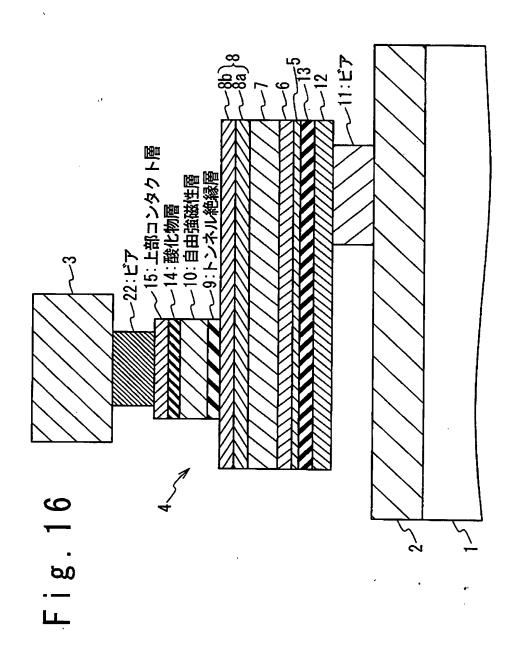
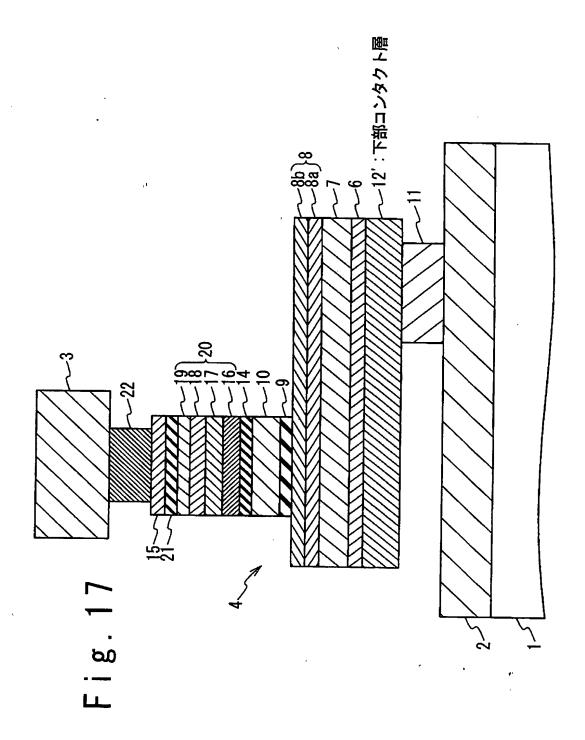
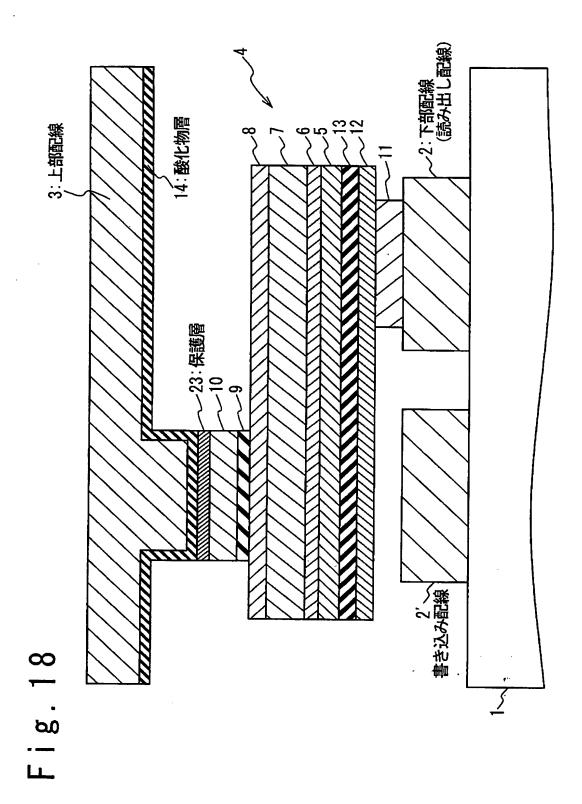


Fig. 15









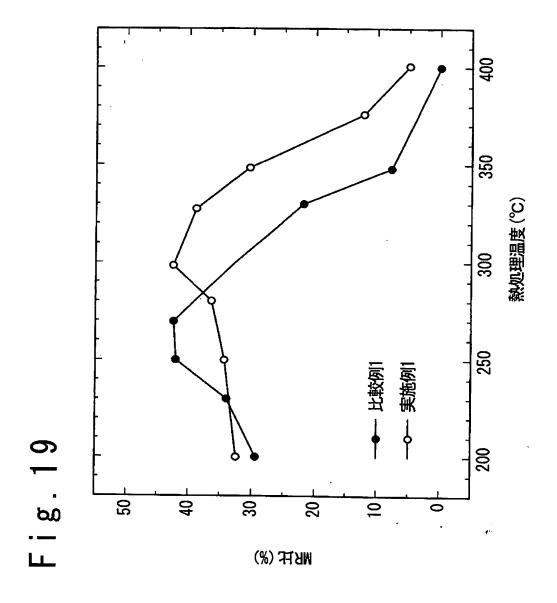


Fig. 20

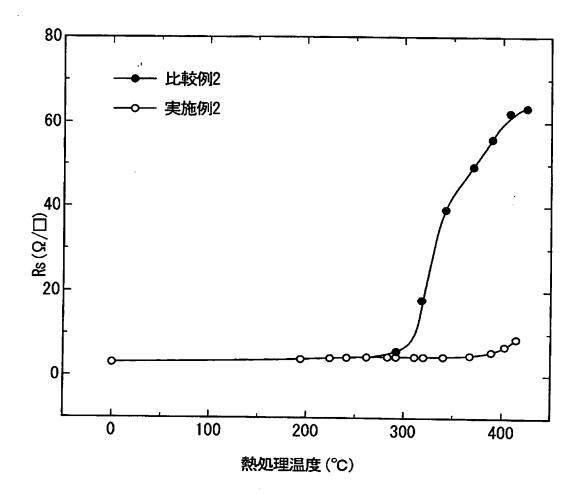
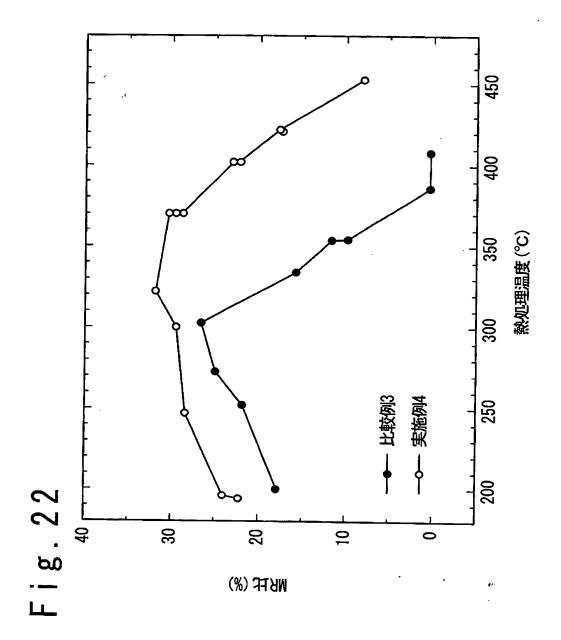


Fig. 21

	酸化物層13に対応する	熱処理速度と熱処理後のシート抵抗(Ω/□)					
	こ対心する	なし	300°C	350°C	400°C		
比較例2	なし	4. 5	6. 2	44. 3	53. 5		
実施例2	Al <sub>2</sub> O <sub>3</sub> (1nm)	4. 3	4. 2	4	5. 1		
実施例3	Mgo(1nm)	4. 7	4. 2	4. 5	5. 1		



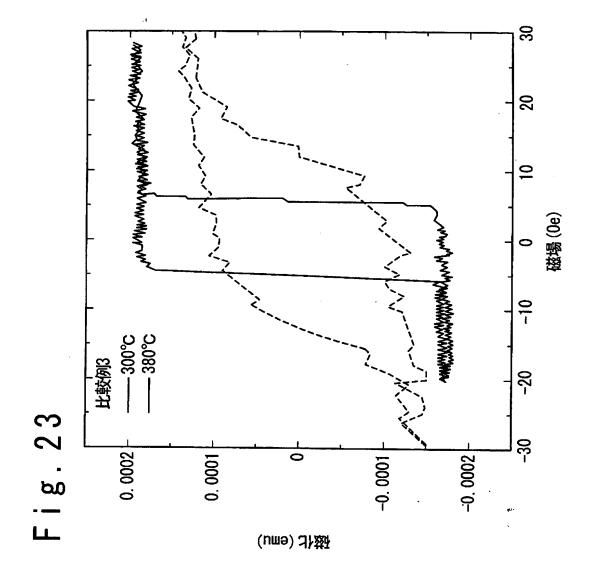


Fig. 24

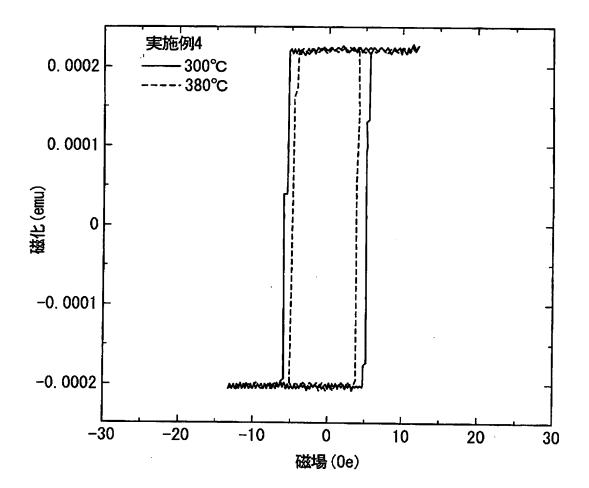
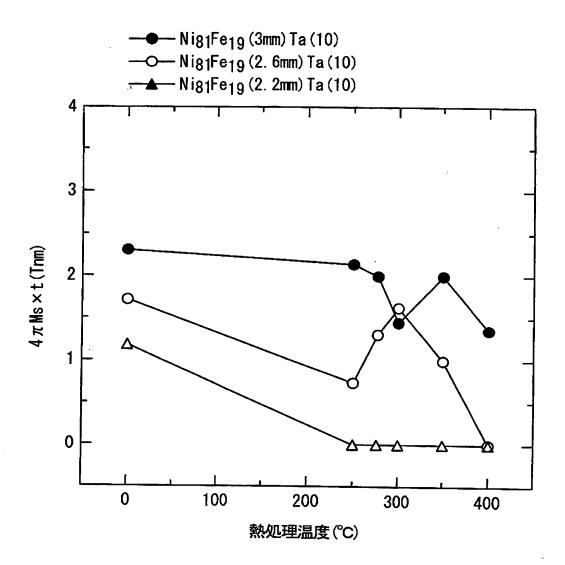
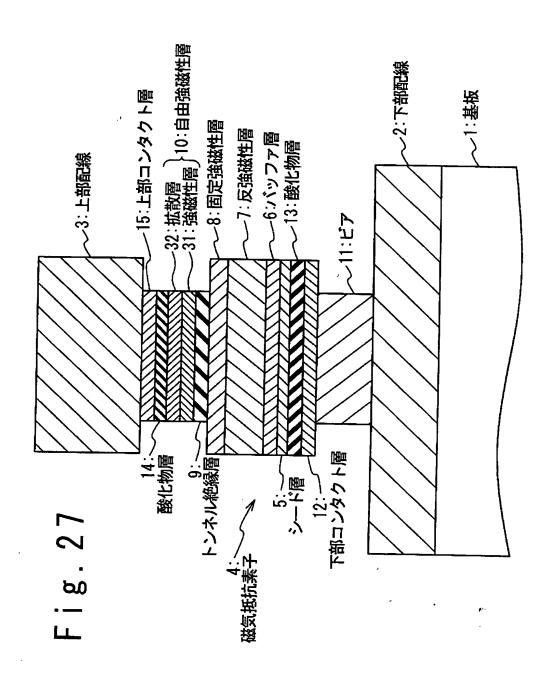


Fig. 25

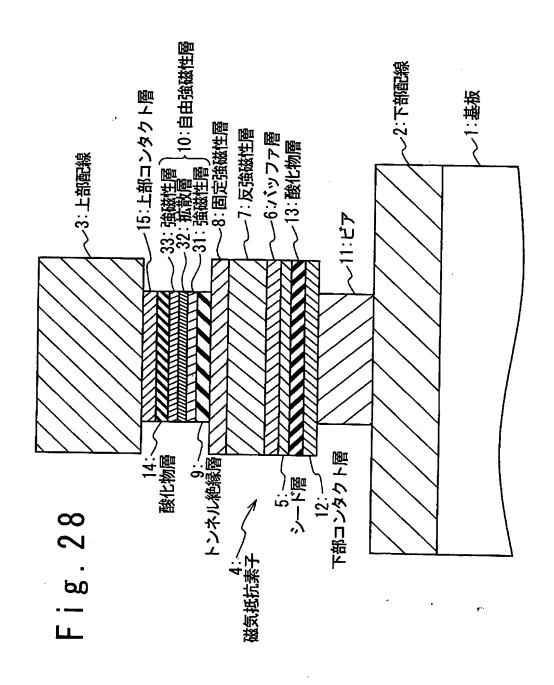
	酸化物層14 に対応する 層	熱処理速度と熱処理後の自由層飽和磁化(emu/cc)						
		なし	200°C	300℃	380°C	400°C		
比較例4	なし	744	736	692	455	35		
比較例5	なし	748	744	724	633	610		
実施例5	Al <sub>2</sub> O <sub>3</sub> (1nm)	783	787	775	771	772		
実施例6	Mgo(1nm)	775	771	775	774	773		

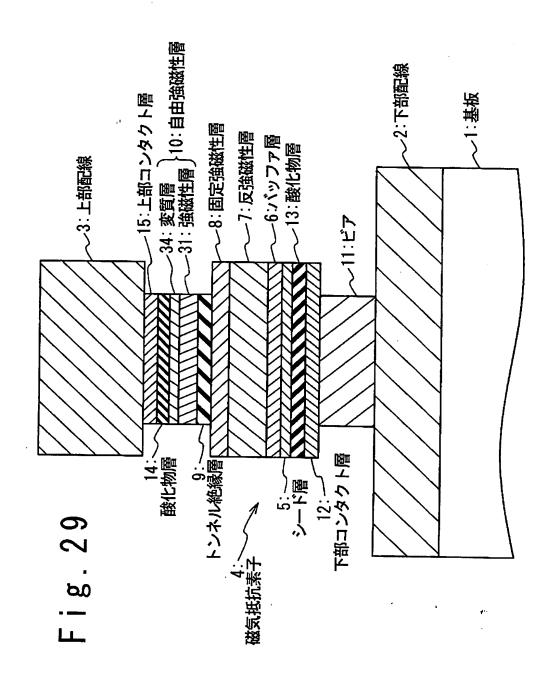
Fig. 26

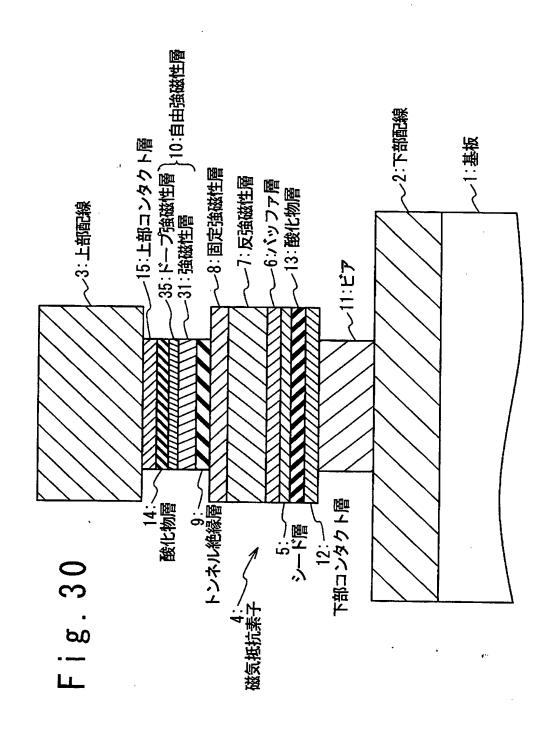




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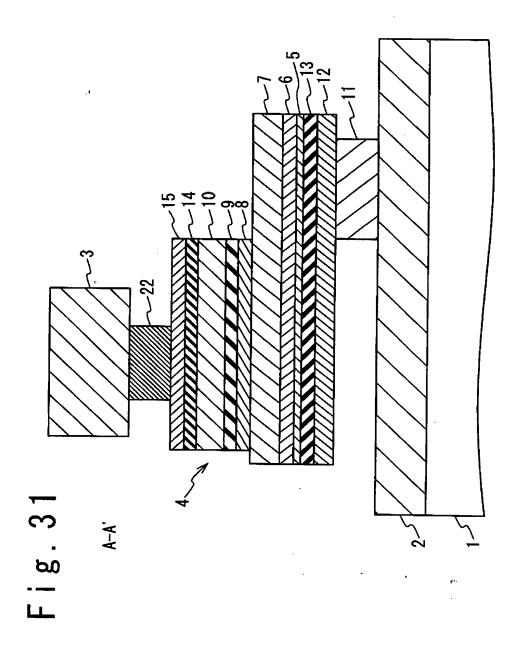


Fig. 32

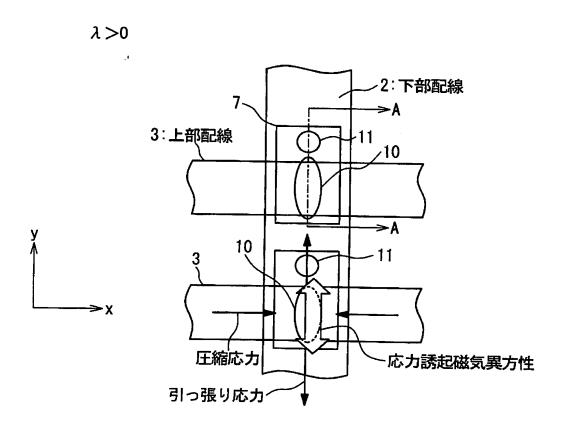


Fig. 33

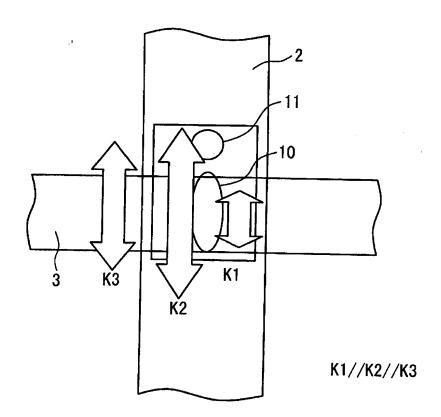


Fig. 34

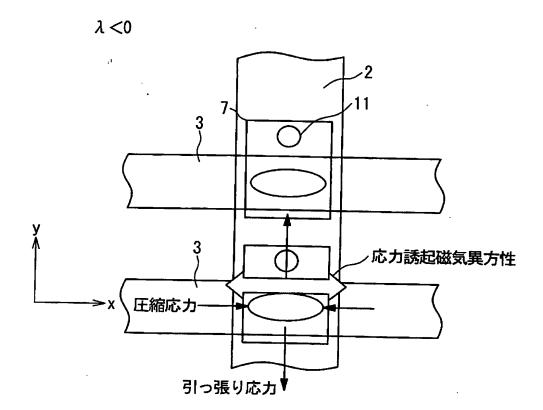


Fig. 35

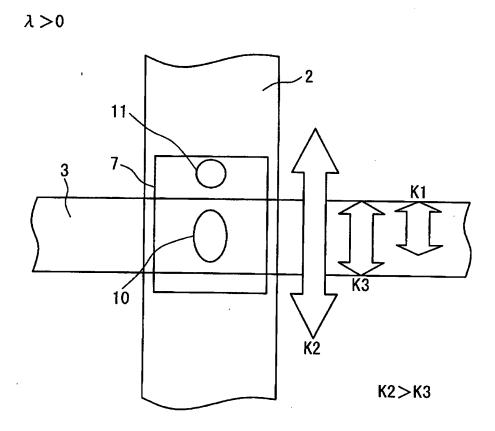


Fig. 36

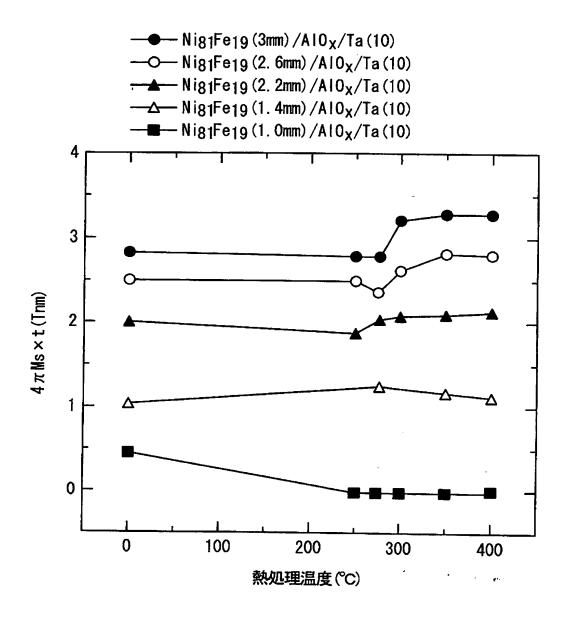


Fig. 37

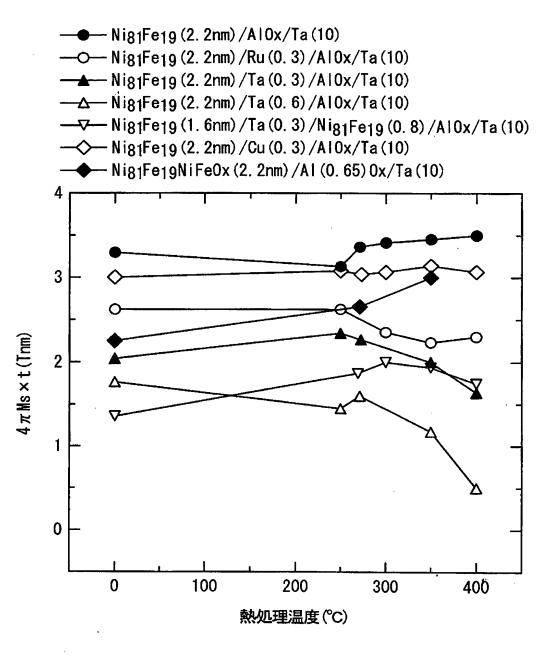


Fig. 38

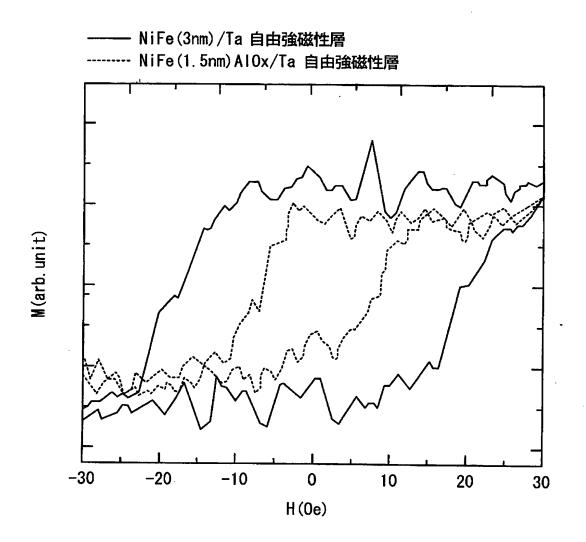


Fig. 39A

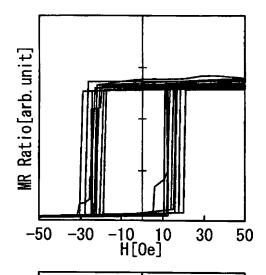


Fig. 39B

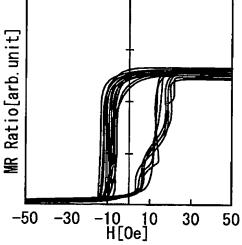


Fig. 39C

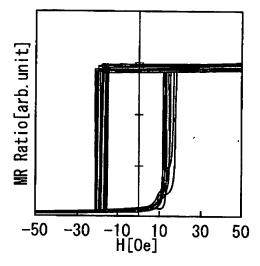


Fig. 40

